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In the Claims

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- 1. (Currently Amended) An organic electroluminescent device comprising: a substrate:
- a thin film transistor formed on the substrate;
- a first electrode electrically coupled to the thin film transistor;
- a chemical vapor deposition insulating film having a low dielectric constant formed on the first electrode and the substrate, the chemical vapor deposition film having an opening portion for exposing the first electrode;
- an organic electroluminescent layer <u>forming formed on</u> a base and a sidewall <u>in</u> of the opening portion without filling the opening; and
 - a second electrode formed on the organic electroluminescent layer.
- 2. (Previously Presented) The device as claimed in claim 1, wherein the chemical vapor deposition insulating film comprises SiOC.
- 3. (Previously Presented) The device as claimed in claim 1, wherein the chemical vapor deposition insulating film has a dielectric constant less than about 3.5.
- 4. (Previously Presented) The device as claimed in claim 1, wherein the chemical vapor deposition insulating film is formed to have a thickness more than about 1 μm.
 - 5. (Currently Amended) An organic electroluminescent device comprising: a substrate;
- a thin film transistor formed on the substrate and having a gate insulating film, a gate electrode, and source/drain electrodes;
 - a passivation layer formed on the thin film transistor and the substrate;
- a pixel electrode formed on the passivation layer so as to be connected with the thin film transistor;
- a chemical vapor deposition insulating film having a low dielectric constant formed on the pixel electrode and the passivation layer, the chemical vapor deposition insulating film

having an opening portion for exposing the pixel electrode;

an organic electroluminescent layer <u>forming formed on</u> a base and a sidewall <u>in</u> of the opening portion without filling the opening portion; and

a metal electrode formed on the organic electroluminescent layer and the chemical vapor deposition insulating film having a low dielectric constant.

- 6. (Previously Presented) The device as claimed in claim 5, wherein the chemical vapor deposition insulating film comprises SiOC.
- 7. (Previously Presented) The device as claimed in claim 5, wherein the chemical vapor deposition insulating film has a dielectric constant less than about 3.5.
- 8. (Previously Presented) The device as claimed in claim 5, wherein the chemical vapor deposition insulating film has a thickness more than about 1 µm.
- 9. (Previously Presented) The device as claimed in claim 5, wherein the chemical vapor deposition insulating film and an edge portion of the pixel electrode overlap by more than about 1 μm.
 - 10. (Currently Amended) An organic electroluminescent device comprising: a substrate;
 - a thin film transistor formed on the substrate;
 - a stripe-shaped first electrode electrically coupled to the thin film transistor;
- a chemical vapor deposition insulating film having a low dielectric constant formed on the fist electrode and the substrate, the chemical vapor deposition insulating film having an opening portion formed on the first electrode with a tapered shape;

an organic electroluminescent layer forming a base and a sidewall in formed on the opening portion; and

a stripe-shaped second electrode formed on the organic electroluminescent layer, the stripe-shaped second electrode being arranged to cross the first electrode.

- 11. (Previously Presented) The device as claimed in claim 10, wherein the chemical vapor deposition insulating film is comprised of SiOC.
- 12. (Previously Presented) The device as claimed in claim 10, wherein the chemical vapor deposition insulating film has a dielectric constant less than about 3.5.
- 13. (Previously Presented) The device as claimed in claim 10, wherein the chemical vapor deposition insulating film has a thickness more than about 1 μ m.